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UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Confirmation No.: 5596

Juichiro UKON et al.

Art Unit: 2877

Serial No.: 09/986,656

Examiner: K. Geisel

Filed: November 9, 2001

Docket No.: 103120-00027

For: METHOD FOR MONITORING AND/OR CONTROLLING THE STATUS  
OF A PLASMA IN A PLASMA SPECTROMETER AND SPECTROMETER  
FOR IMPLEMENTING SUCH A METHOD

**SUBMISSION OF CORRECTED FORMAL DRAWINGS**

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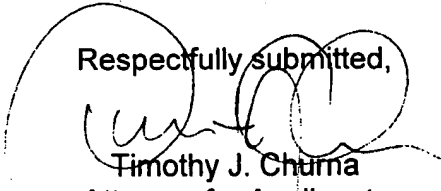
July 5, 2005

Sir:

In response to the Notice Regarding Drawings dated June 21, 2005, attached are the corrected formal drawings to replace corresponding sheets filed with the original application. Applicants hereby submit the corrected drawings as required and approved by the Examiner. It is respectfully submitted that these formal drawings overcome the objection to the originally filed drawing.

If any fees are required with respect to this paper, please charge our Deposit Account No. 01-2300.

Respectfully submitted,

  
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